

ABSTRACT

The purpose of the present invention is to provide an attachment suppression/removal method with which it is possible to reliably suppress the attachment of a sessile organism to a structure or reliably remove a sessile organism from a structure. This attachment suppression/removal method includes irradiating a structure having a sessile organism attached thereto with light on the basis of a light irradiation amount set for every sessile organism, thereby suppressing the attachment of the sessile organism to the structure or removing the sessile organism attached to the structure. The light irradiation amount is 160 Whm^{-2} or more, and the irradiance of the light irradiated on the basis of the light irradiation amount is 20 Wm^{-2} or more.